



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Wang, et al.

Serial No.: 10/800,112

Confirmation No.: 8920

Filed: March 12, 2004

For: Method of Depositing An
Amorphous Carbon Film for
Metal Etch Hardmask
Application

§
§
§
§
§
§
§
§
§
§
§
§

Group Art Unit: 1765

Examiner: Mahmoud Dahmene

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING
37 CFR 1.8

I hereby certify that this correspondence is being deposited on
February 6, 2006, with the United States Postal Service as
First Class Mail in an envelope addressed to: Mail Stop
Amendment, Commissioner for Patents, P.O. Box 1450,
Alexandria, VA 22313-1450.

02/06/06
Date

Brian K. Hrna
Signature

RESPONSE TO OFFICE ACTION DATED OCTOBER 5, 2005

In response to the Office Action dated October 5, 2005, having a shortened statutory period for response extended one-month to expire on February 6, 2006, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/008245/BKH, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 7 of this paper.